	Application No.	Applicant(s)
Notice of Allowability	10/605,122	CHANG, KENT KUOHUA
	Examiner	Art Unit
	Walter L. Lindsay, Jr.	2812
The MAILING DATE of this communication appears on the cover sheet with the correspondence address All claims being allowable, PROSECUTION ON THE MERITS IS (OR REMAINS) CLOSED in this application. If not included herewith (or previously mailed), a Notice of Allowance (PTOL-85) or other appropriate communication will be mailed in due course. THIS NOTICE OF ALLOWABILITY IS NOT A GRANT OF PATENT RIGHTS. This application is subject to withdrawal from issue at the initiative of the Office or upon petition by the applicant. See 37 CFR 1.313 and MPEP 1308. 1. This communication is responsive to Amendment filed 10/11/2004. 2. The allowed claim(s) is/are 1-3,5-17 and 19-25. 3. The drawings filed on 10 September 2003 are accepted by the Examiner. 4. Acknowledgment is made of a claim for foreign priority under 35 U.S.C. § 119(a)-(d) or (f). a) All b) Some* c) None of the:		
1. Certified copies of the priority documents have been received.		
 2. Certified copies of the priority documents have been received in Application No. 3. Copies of the certified copies of the priority documents have been received in this national stage application from the International Bureau (PCT Rule 17.2(a)). * Certified copies not received: Applicant has THREE MONTHS FROM THE "MAILING DATE" of this communication to file a reply complying with the requirements noted below. Failure to timely comply will result in ABANDONMENT of this application. 		
THIS THREE-MONTH PERIOD IS NOT EXTENDABLE. 5. A SUBSTITUTE OATH OR DECLARATION must be submitted. Note the attached EXAMINER'S AMENDMENT or NOTICE OF INFORMAL PATENT APPLICATION (PTO-152) which gives reason(s) why the oath or declaration is deficient.		
6. CORRECTED DRAWINGS (as "replacement sheets") must be submitted.		
(a) ☐ including changes required by the Notice of Draftsperson's Patent Drawing Review (PTO-948) attached		
1) hereto or 2) to Paper No./Mail Date		
(b) ☐ including changes required by the attached Examiner's Amendment / Comment or in the Office action of Paper No./Mail Date		
Identifying indicia such as the application number (see 37 CFR 1.84(c)) should be written on the drawings in the front (not the back) of each sheet. Replacement sheet(s) should be labeled as such in the header according to 37 CFR 1.121(d).		
7. DEPOSIT OF and/or INFORMATION about the deposit of BIOLOGICAL MATERIAL must be submitted. Note the attached Examiner's comment regarding REQUIREMENT FOR THE DEPOSIT OF BIOLOGICAL MATERIAL.		
Attachment(s)	5 - 1 Nov. 10 1	mal Datast Application (DTO 450)
1. Notice of References Cited (PTO-892)	_	mal Patent Application (PTO-152)
2. Notice of Draftperson's Patent Drawing Review (PTO-948)	6. ☐ Interview Sum Paper No./Ma	ail Date
 Information Disclosure Statements (PTO-1449 or PTO/SB/0 Paper No./Mail Date 	08), 7. ☐ Examiner's An	nendment/Comment
4. Examiner's Comment Regarding Requirement for Deposit of Biological Material	8. ⊠ Examiner's Sta 9. □ Other	atement of Reasons for Allowance

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DETAILED ACTION

This Office Action is in response to an Amendment filed 10/11/2004.

Currently, claims 1-3, 5-17 and 19-25 are pending.

Allowable Subject Matter

1. Claims 1-3, 5-17 and 19-25 are allowed.

2. The following is an examiner's statement of reasons for allowance: the prior art, either singly or in combination fails to anticipate or render obvious, the limitations of:

... performing a doping process on the silicon layer to form a heavily doped drain region beside the lightly doped drain region, and on the gate structure, wherein a dosage of the doping process is about 3E15 to about 5E15 ions/cm², as required by claim 1;

introducing n-type dopants to the silicon substrate to form source/drain regions in the substrate beside the gate electrode and to the gate electrode, wherein a dosage of the n-type dopants is about 3E15 ions/cm2 to about 5E15 ion/cm 2;

forming a cap layer over the doped polysilicon gate, as required by claim 16; and ... implanting arsenic ions to the strained silicon layer and a top surface of the silicon germanium layer to form a heavily doped drain region beside the lightly doped drain region and to the gate structure;

forming a cap layer over the substrate;

performing a rapid thermal annealing process;

removing the cap layer; and

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forming a nickel silicide layer atop the gate structure and the heavily doped drain region, as required by claim 23.

Any comments considered necessary by applicant must be submitted no later than the payment of the issue fee and, to avoid processing delays, should preferably accompany the issue fee. Such submissions should be clearly labeled "Comments on Statement of Reasons for Allowance."

Conclusion

Any inquiry concerning this communication or earlier communications from the examiner should be directed to Walter L. Lindsay, Jr. whose telephone number is (571) 272-1674. The examiner can normally be reached on Monday-Thursday.

If attempts to reach the examiner by telephone are unsuccessful, the examiner's supervisor, John F Niebling can be reached on (571) 272-1679. The fax phone number for the organization where this application or proceeding is assigned is 703-872-9306.

Information regarding the status of an application may be obtained from the Patent Application Information Retrieval (PAIR) system. Status information for published applications may be obtained from either Private PAIR or Public PAIR. Status information for unpublished applications is available through Private PAIR only. For more information about the PAIR system, see http://pair-direct.uspto.gov. Should you have questions on access to the Private PAIR system, contact the Electronic Business Center (EBC) at 866-217-9197 (toll-free).

Walle L human November 8, 2004

/ John F. Niebling Supervisory Patent Exeminer Technology Osmar 2006